

Optical switch integrated OCT system

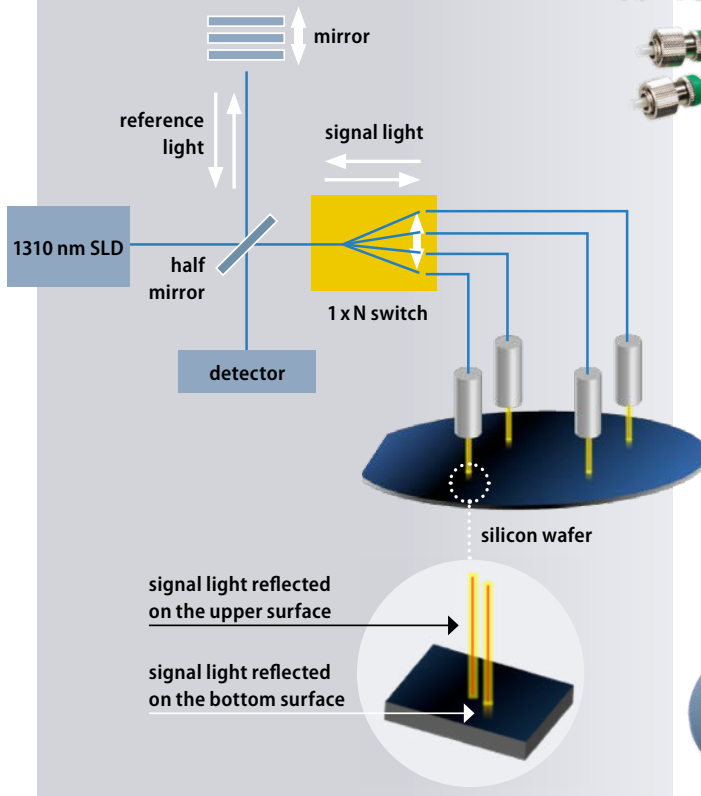
(Optical coherence tomography)

FiberSwitch®

Light Switching for Optical Systems



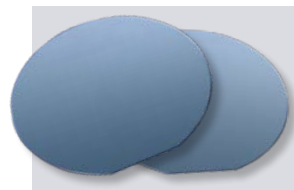
Thickness measurement of silicon wafer



In an OCT measurement, the thickness of a silicon wafer can be measured accurately, by detecting the reflection lights reflected on the upper surface and the bottom surface respectively.

By integrating an optical switch in an OCT measurement system, the thickness of a large size wafer can be measured efficiently.

LEONI supplies various types of singlemode switches, including polarization maintaining switches, suited for OCT measurements.



Spectral range		VIS	NIR I	NIR II	IR
Number of channels		1x2, 1x4, 1x8, 1x12 and 1x16 2x2, 2x4 and 2x8 (other channel counts on request)			
Operating wavelength	[nm]	400 – 670	600 – 900	900 – 1200	1260 – 1380 1480 – 1650
Switching frequency	[s ⁻¹]	≤ 50			

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